

Serial No.
10/662.215

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Applicants:
Venkata R. Gorantla, et al

LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary.)

Filing Date
12 September 2003

Group
To Be Assigned

U.S. PATENT DOCUMENTS

Examiner Initial*	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EC	6540,935 B2	04-01-2003	Lee et al.			
	6,491,843 B1	12-10-2002	Srinivasan et al.			
	6,485,355 B1	11-26-2002	Economikos et al.			
	6,468,910 B1	10-22-2002	Srinivasan et al.			
	6,299,659 B1	10-09-2001	Kido et al.			
	6,218,305 B1	04-17-2001	Hosali et al.			
	6,171,180 B1	01-09-2001	Koutny, Jr. et al.			
	6,132,637	10-17-2000	Hosali et al.			
	6,042,741	03-28-2000	Hosali et al.			
	6,027,554	02-22-2000	Kodama et al.			
	5,958,794	09-28-1999	Bruxvoort et al.			
	5,876,490	03-02-1999	Ronay			
	5,759,917	06-02-1998	Grover et al.			
	5,738,800	04-14-1998	Hosali et al.			

FOREIGN PATENT DOCUMENTS

Examiner Initial*	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

"Study of pattern density effects in chemical-mechanical planarization using fixed abrasive pads," by Venkata R. Gorantla et al., accepted for publication in Journal of Electrochemical Society (2003).

"Effects of mixed abrasives in chemical mechanical polishing of oxide films." by Zhenyu Lu, et al., to be published in Journal of Materials Research, October 2003, Vol. 18, No. 10.

EXAMINER

Eric Chen

DATE CONSIDERED

6/22/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.